

Pranoy Deb Shuvra

List of Publications by Year in descending order

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citing authors

#	ARTICLE	IF	CITATIONS
1	Total-Ionizing-Dose Effects in Piezoresistive Micromachined Cantilevers. IEEE Transactions on Nuclear Science, 2017, 64, 263-268.	2.0	10
2	Axial asymmetry for improved sensitivity in MEMS piezoresistors. Journal of Micromechanics and Microengineering, 2016, 26, 095014.	2.6	8
3	Proton-Induced Displacement Damage and Total-Ionizing-Dose Effects on Silicon-Based MEMS Resonators. IEEE Transactions on Nuclear Science, 2018, 65, 34-38.	2.0	7
4	Near-Surface Electronic Contribution to Semiconductor Elasticity. Physical Review Applied, 2017, 8, .	3.8	5
5	Dose-Rate Effects on the Total-Ionizing-Dose Response of Piezoresistive Micromachined Cantilevers. IEEE Transactions on Nuclear Science, 2018, 65, 58-63.	2.0	4
6	Surface carrier concentration effect on elastic modulus of piezoelectric MEMS silicon cantilevers. , 2017, , .		3
7	GaN/AlN Heterostructure Micromechanical Self-Sustained Oscillator for Middle Ultraviolet (MUV) Light Detection. , 2019, , .		2
8	The strain capacitor: A novel energy storage device. AIP Advances, 2014, 4, 127158.	1.3	1
9	Dopant-Type and Concentration Dependence of Total-Ionizing-Dose Response in Piezoresistive Micromachined Cantilevers. IEEE Transactions on Nuclear Science, 2019, 66, 397-404.	2.0	1
10	Dimensional dependence of the radiation damage in microelectromechanical system resonators. Journal Physics D: Applied Physics, 2019, 52, 375101.	2.8	0
11	Buckled beam mechanical memory using an asymmetric piezoresistor for readout. Journal of Micromechanics and Microengineering, 2020, 30, 075006.	2.6	0